

An object of the present invention was to overcome the problems of measurement precision for resonance frequencies of high-frequency oscillators when using conventional pi-circuit measurement methods. The present invention contemplates multiple, high-frequency oscillators of the smallest unit formed on a large wafer. A second electrode is grounded. Probes are put into contact with an input terminal, formed from one of the main electrodes and the second electrode, and an output terminal, formed from the other main electrode and the second electrode. Measurement is performed using the S parameter method. As a result, high-precision resonance frequency characteristics can be obtained.

While the second electrode surrounds the main electrode in Fig. 4 and the specification states that the second electrodes formed on the main surfaces of the crystal substrate can be short-circuited and grounded, there is no disclosure that “an input terminal is formed from one of the main electrodes and the second electrode and an output terminal is formed from the other main electrode and the second electrode.” Also, the development of the “input terminal and the output terminal” of the present invention addresses the problems of measurement precision described above. There is not even a suggestion that this type of problem was considered or taken into account in the structure shown in Fig. 4.

As a result, it is clear that the structure of the invention in claim 4 differs from that of Fig. 4.

Furthermore, new claim 7, which corresponds to the second embodiment shown in Fig. 2, is also patentable. As described above, there is no description or suggestion of “the input terminal and the output terminal” in the crystal oscillator structure shown in the background technology in Fig. 4.

As described above, the claimed invention and the background technology have completely different structures, and these different structures result in completely different operations and advantages. Thus, the claimed invention is not identical to the background technology and clearly is not something that could be easily derived from the background technology.

Applicant thanks the Examiner for the indication of allowable subject matter in claims 5 and 6. With the amendment above of claim 5, claims 5 and 6 are now both allowable.

In view of the above amendments and remarks, Applicant respectfully submits that the present application is in immediate condition for allowance. Accordingly, the Examiner is respectfully requested to pass the present application to issue.

Respectfully submitted,

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